

16cm Source

Our 16cm RF ion beam source is an industry workhorse, serving as the dominant deposition source in ion beam deposition (IBD) systems around the world. With an output capacity of 600mA, 800mA, or even 1000mA this dynamic and versatile source can satisfy a huge array of needs in deposition and large-scale lon assist processes. Available with standard molybdenum, collimated graphite, or titanium grids, this source can be used in almost any type of contamination-sensitive ion beam process. This 16cm source can even be equipped with modulators allowing it to be used in metal deposition and etch processes, an operational regime normally challenging for RF ion beam. The source provides a 16cm ion beam which is then shaped by the choice of grids. Convergent, divergent, collimated, and even multi-focal point grids are available with this source. Please refer to the grid selection table below.

Radio frequency – requires a mounting flange

RF Power, DC Bias, Control, and RFN Operation

Used only with I-Beam 701 power supplies

Includes Matching Network & Controller for source

Adapts connections to an Ion-Tech style configuration

Sputter

Sputter

Sputter

Sputter

Sputter

Sputter

Assist

Etch

Assist

Each flange has a RFN matching network.

1000mA / 1500V Beam configuration, requires separate RF Generator

3 grid, 104/72/40cm FPs, 0.065" spacing, .020" thick

3 grid, 104/72/40cm FPs, 0.065" spacing, .015" thick

3 grid, 104/72cm FPs, 0.065" spacing, .020" thick

3 grid, 104/72/40cm FPs, 0.065" spacing

I-Beam 703 Cable Kit with beam, RFN and RF cables

3 grid, 66cm FP, Divergent

3 grid, 66cm FP, Convergent

3 grid, 66cm FP, Convergent

Moly, 3 grid, 33cm FP

3 grid, Graphite, flat

I-Beam 701/703 Cable Kit for use with 1kW RF Generator



FLANGE/EXTENSION MOUNT

Neutralizer

Neutralizer

RF Matching

RF Generator

Adapter Box

3 Focal Point

2 Focal Point

66cm FP, Div.

66cm FP.

Convergent

Collimated

33cm FP, Div.

GRID OPTIONS

Cable Kits

Common

Flanges

504424B

504854A

504891A

504855A

505914A

505311A

505752A

507128A

IBOX-104

504296B

5042961

507103A

504137A

504373B

504599A

504851A

504455A

504822A

IBEAM 701-4

Power Supplies IBEAM 703-1 series

RFN

2¾" CF RFN Flange

4.5" CF RFN Flange

6" CF RFN Flange

1000W RF Generator

Source RF

Molybdenum

Molybdenum

Molybdenum

Molybdenum

Molybdenum

Molybdenum

Titanium

Titanium

Graphite

The Flange and Extension Mount options for this ion source offer fixed positioning for maximum process repeatability. The Flange Mount places the source directly against the flange using the smallest amount of space, while the Extension Mount stands off the flange with fixed posts. The minimum flange size for these options is a 16.5-inch Conflat. These packages include a high-voltage cover on the atmosphere side of the flange to which the RF Matching Network mounts directly. Also provided are connection points for cooling water, source gas, and DC bias.





▲INTERNAL MOUNT

Using an Internal Mount configuration places the ion source loosely inside the vacuum chamber, allowing angular (pointing) adjustment to suit process needs. The maximum distance from the RF vacuum feedthrough for this configuration is 18-inches. This option allows some freedom of location of the ion source and the ability to use multiple smaller feedthroughs instead of one large feedthrough. The standard flanges for this configuration are three 2.75 inch Conflat. Other flange combinations are available. The RF Matching Network mounts directly to the RF feedthrough.

plasmaprocessgroup.com

it in our is an e	2001y 17 1130 P	Tovided are con	riceción points n	or cooming water, s	.041 00 843, 0	ina be blas.	
NOMINAL PERFORMANCE DATA - USING ARGON @ 18 SCCM							
	BEAM		ACCELERATOR		RF POWER	NEUTRALIZER	
Voltage (V)	Curren	t (mA) Voltage	(V) Current	(mA) Forward (W) Reflect	ed (W) Emission (mA)	
250	300	550	11	199	0	450	
500	300	400	8	193	0	450	
750	450	300	17	266	0	675	
1000	600	350	18	347	1	900	
1250	600	250	15	352	2	900	
1250	800	400	24	485	4	1200	
1500	800	250	20	475	3	1200	
250-1500	100 floo	or 200	~3	~94	1	150	
OPTIONS & ACCESSORIES							
Ion Source	16RFC)8 Standar	rd Ion Source	Used for 600mA Configuration			
	16RF	HC Advanc	Advanced Ion Source Requir		uired for 800mA and 1000mA configuration		
Interface Ki	ts 50490)1A Flange	Mount	Includes Vacuum Feedthroughs and vacuum-side connections to source for RF Power, DC bias, cooling water, and gas			
	50490)2A Extensi	on Mount				
	50490)3A Interna	l Mount				